



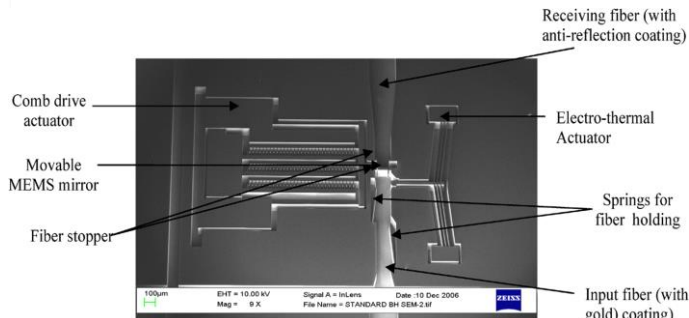
David Hays, *Engineer*

David holds a PhD in Materials Science and Engineering from the University of Florida. In addition, he has over ten years of industry experience working at Sony Semiconductor and GE Global Research. Within the fields of MEMS and nanotechnology he has written over 60 publications and holds numerous patents.

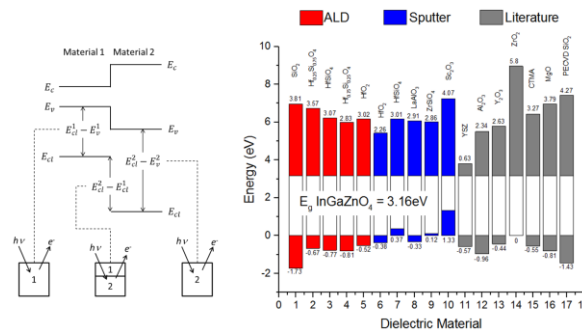
Expertise Examples

Performed extensive research in wet and plasma etching of semiconductor materials as well as metals and dielectrics, with a focus on selective etching. Experienced in process development of sputter deposition, PECVD, photolithography, and electrochemistry. Expert in process integration of semiconductor devices such as CMOS, MEMS, flexible electronics and compound semiconductors. Six sigma green belt certified and QS9000 qualified with expertise in design of experiments, FMEA and quality control

Tunable, vertical, hybrid MEMS Fabry-Perot interferometer

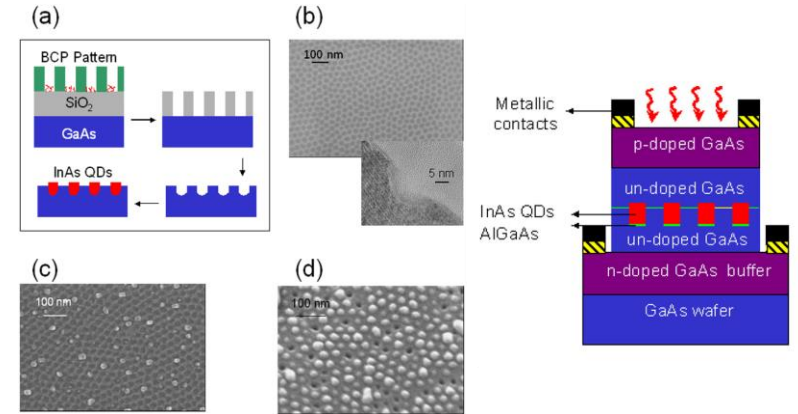


Energy band offsets of gate dielectrics on InGaZnO using x-ray photoelectron spectroscopy



Expertise Examples

Templated growth of semiconductor nanostructures through block copolymer lithography for IR photodiodes



Micromirror array for high definition displays

